



IRW

PATENT
81872.0055

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Yosuke INOMATA

Serial No: 10/762,676

Filed: January 22, 2004

For: MULTICRYSTALLINE SILICON
SUBSTRATE AND PROCESS FOR
ROUGHENING SURFACE
THEREOF

Art Unit: 1765

Examiner: Not Assigned

STATUS REQUEST

Mail Stop Status Inquiry
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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March 22, 2005

Date of Deposit

Sheila Goldner

Name

Sheila Goldner 03/22/05

Signature

Date

Dear Sir:

This application was filed on January 22, 2004 and receipt by the U.S. Patent and Trademark Office was acknowledged in the Filing Receipt dated April 27, 2004. However, no Office Action has yet been received. Accordingly, Applicants request to be advised of the status of the application, including an indication of when the patent application is expected to be examined.

Please send the undersigned a Status Report on this application.

Respectfully submitted,
HOGAN & HARTSON L.L.P.

Date: March 22, 2005

By:

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